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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventors : Franz LAERMER et al.
Serial No. : 09/720,761
Filed : March 26, 2001
For : METHOD OF PLASMA ETCHING OF SILICON
Examiner : Kin Chan Chen
Art Unit : 1765
Confirmation No. : 5642

Mail Stop AF
Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

NOTICE OF APPEAL

Applicants hereby appeal to the Board of Patent Appeals and Interferences from the decision of the Examiner made in the Final Office Action dated April 10, 2003 finally rejecting claims 19-36.

The Commissioner is hereby authorized to charge payment of the 37 C.F.R. 1.191 Notice of Appeal fee of \$320.00 to the deposit account of Kenyon & Kenyon, Deposit Account No 11-0600. Any additional fees deemed necessary should also be charged to Deposit Account No. 11-0600. Two additional copies of this Notice are enclosed for that purpose.

Respectfully submitted,

10 July 2003

Richard L. Mayer

Reg. No. 22,490

I hereby certify that the enclosed copy of the Notice of Appeal is a true and correct copy of the original filed with the
United States Patent and Trademark Office
in an envelope addressed to the
Mail Stop AF
Commissioner for Patents, P. O. Box 1450, Alexandria, VA 22313-1450
on

Date: 7/10/03

Signature: *Conni Siler*

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